



Attv. Dkt. No. AMAT/5262/CMP/CMP/RKK

Where Application of:

Tsai, et al.

Serial No.: 09/961,134

Confirmation No.: 4110

Filed: September 21, 2001

For: Method and Apparatus For Forming Metal Layers

Group Art Unit: 1753

Examiner: Wong, Edna

MAIL STOP AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

CERTIFICATE OF MAILING

37 CFR 1.8

I hereby certify that this correspondence is being deposited on April 20, 2004, with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

4/20/04

Date _____

Keith R. Zander

Dear Sir:

RESPONSE TO FINAL OFFICE ACTION DATED FEBRUARY 6, 2004

In response to the Final Office Action dated February 6, 2004, having a shortened statutory period for response set to expire on May 6, 2004, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicant believes that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/5262/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

Amendments to the Specification begin on page 2 of this paper. **Amendments to the Claims** are reflected in the listing of claims which begins on page 4 of this paper. **Remarks** begin on page 5 of this paper.